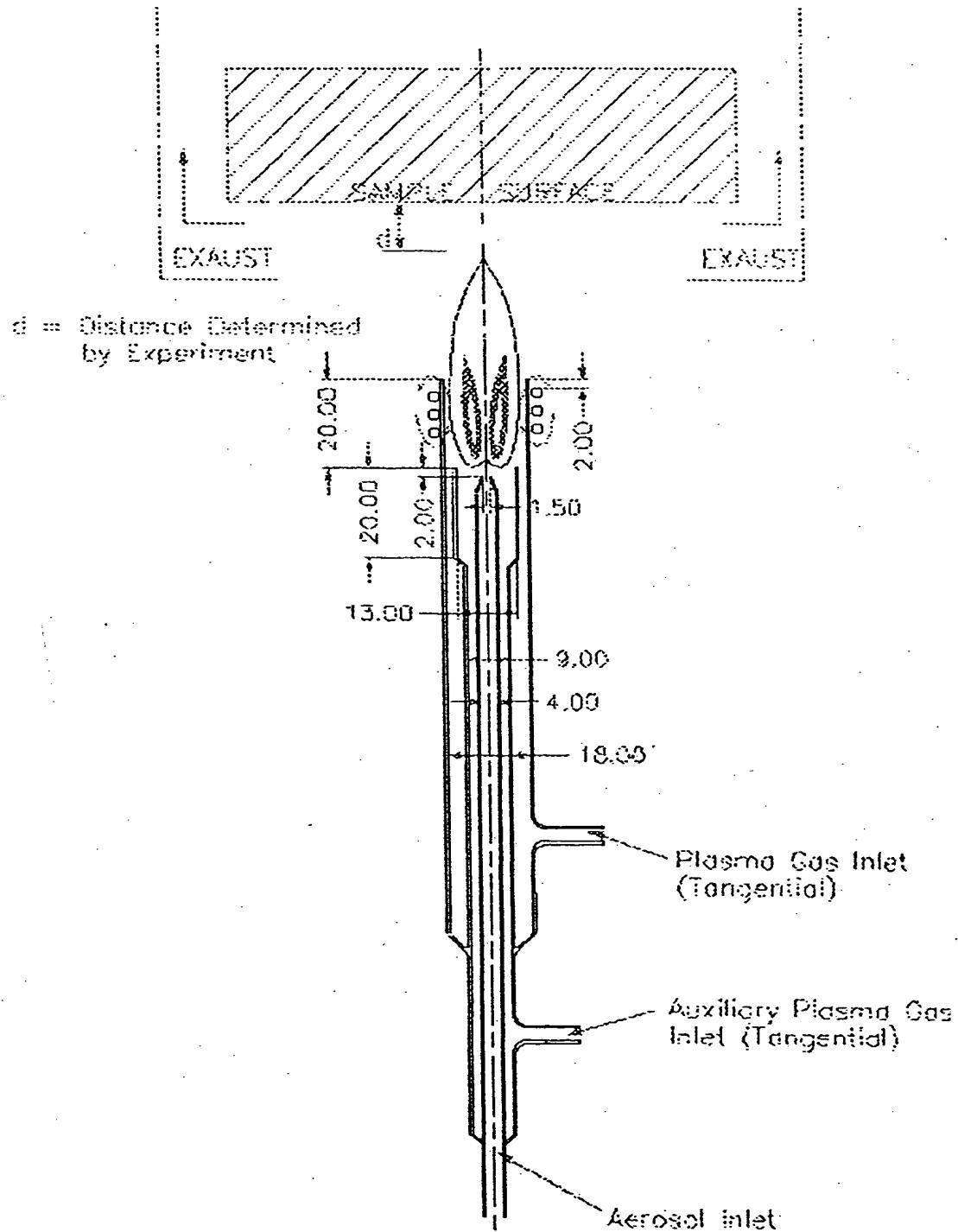


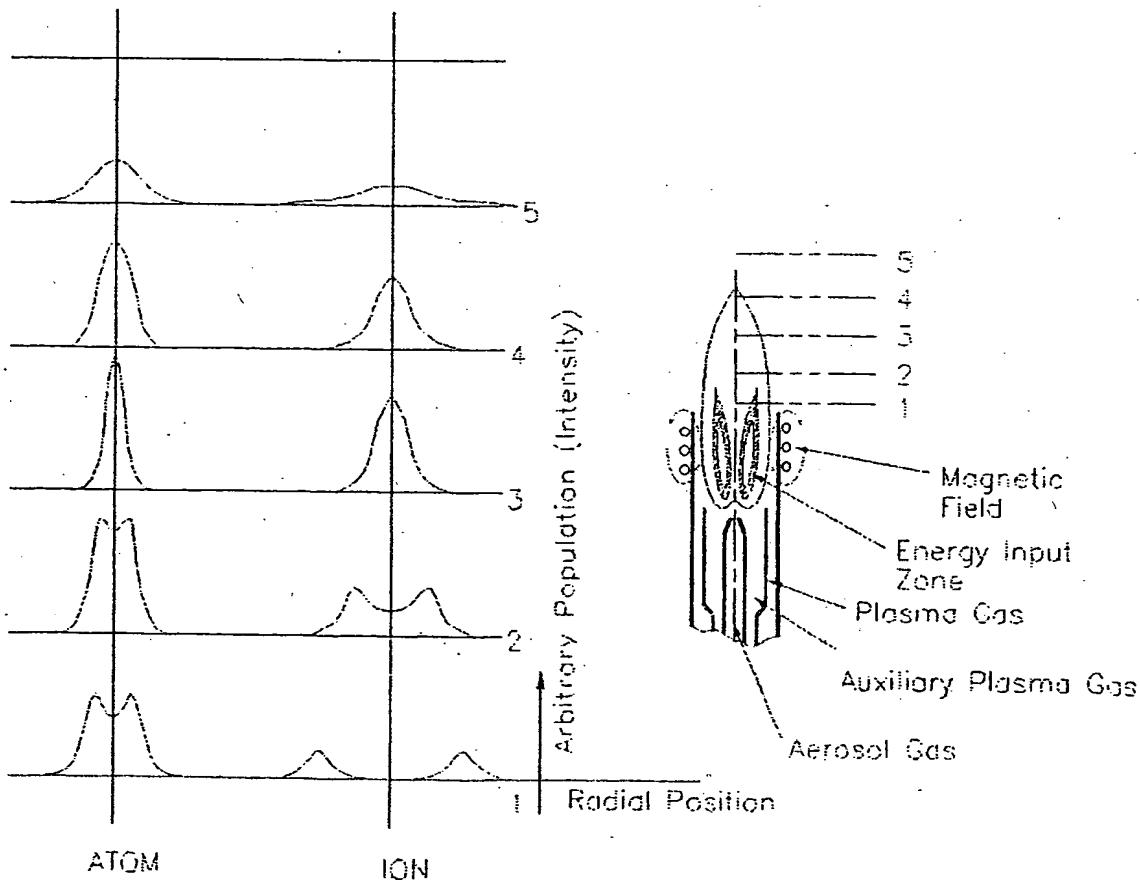
Fig 1: ICP Torch

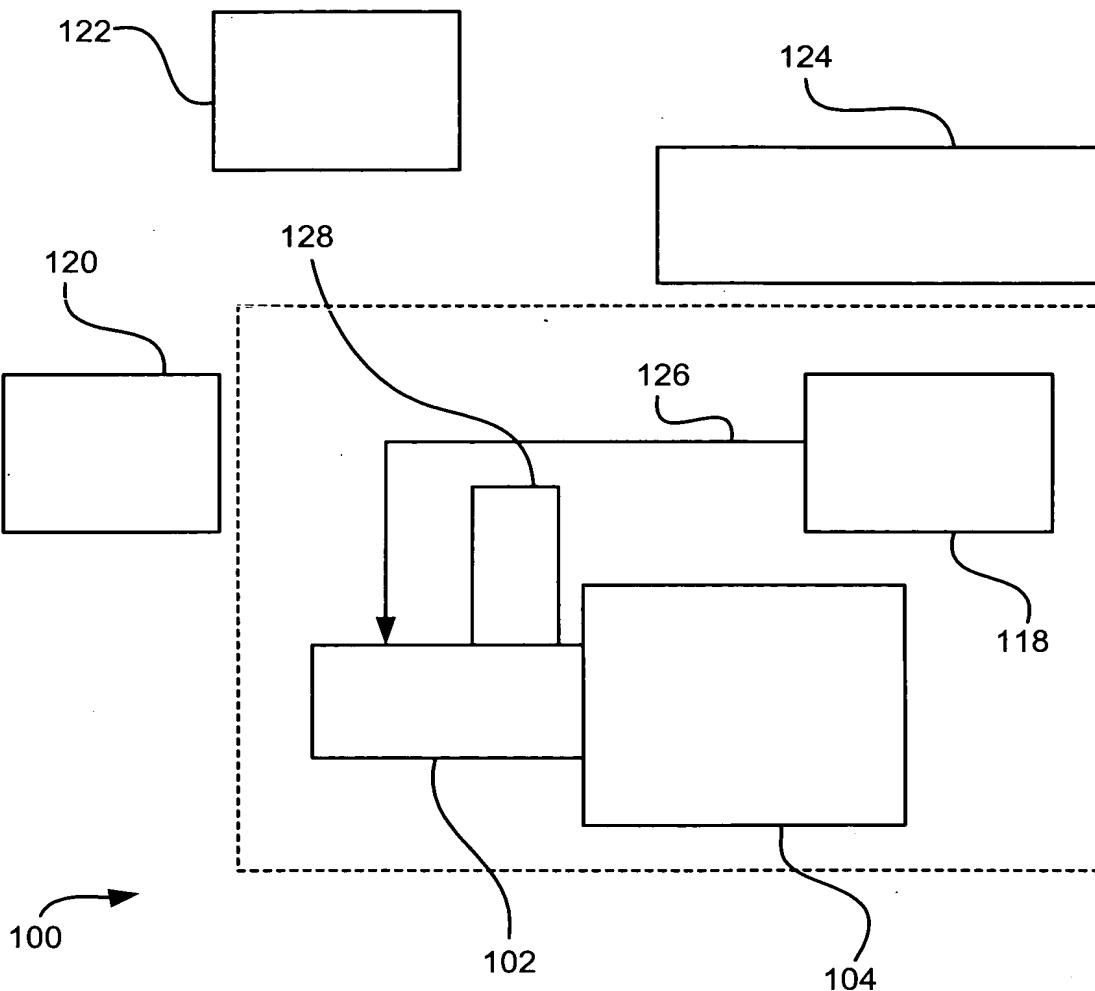


(all measurements are in millimeters)

Fig. 2: Atom and Ion Distribution in the ICP

FIGURE 200200001





**FIG. 3**

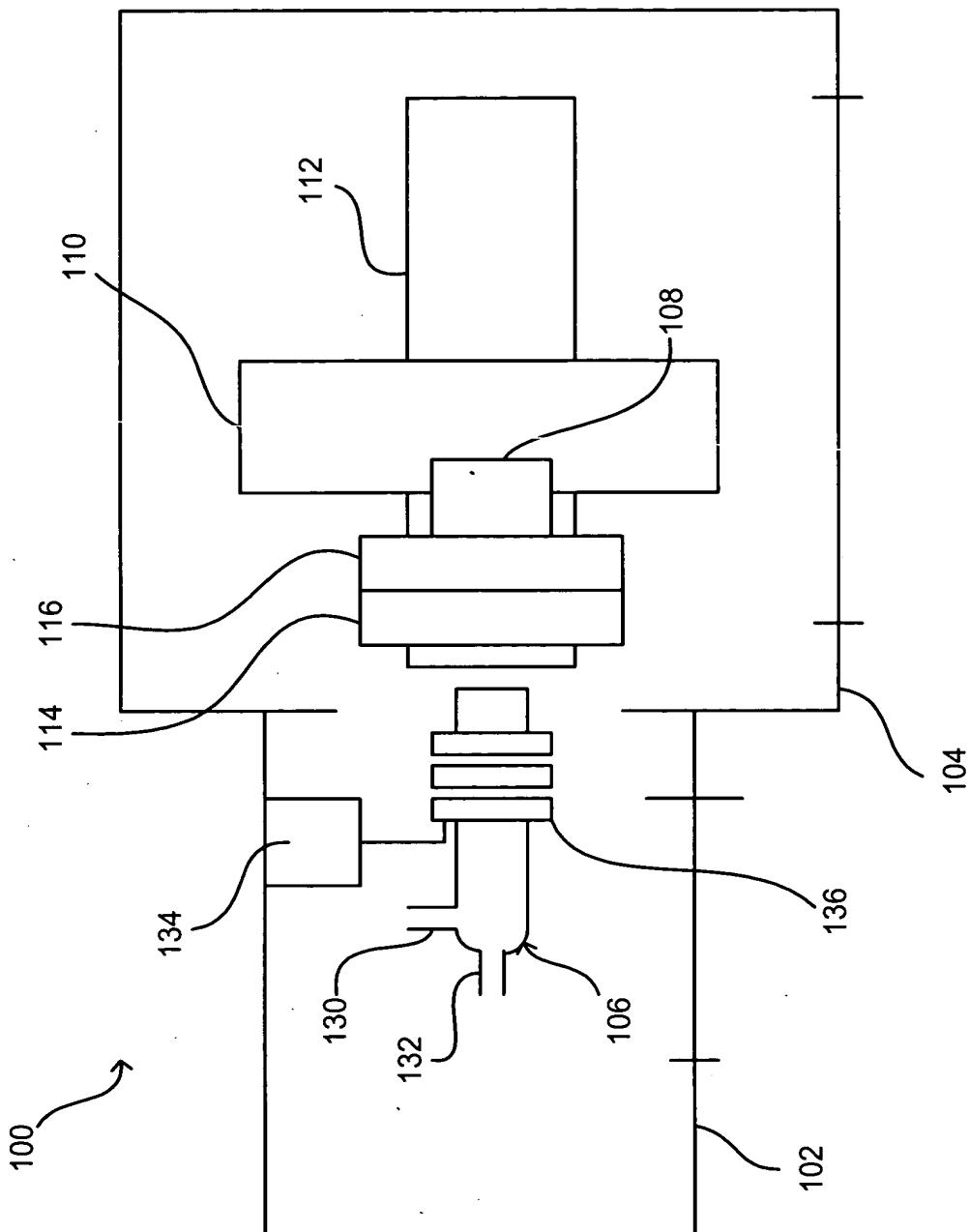
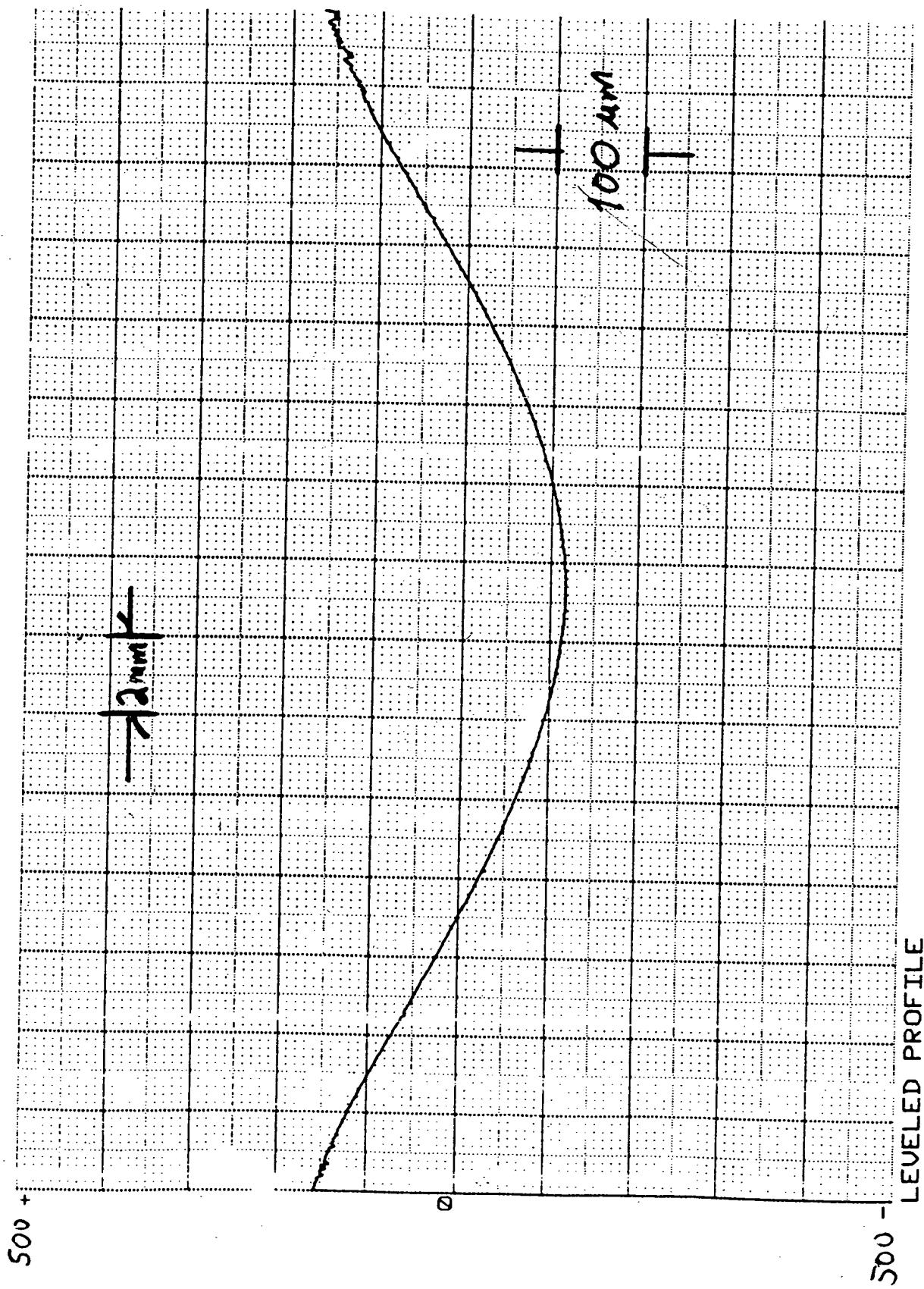


FIG. 4

Title: APPARATUS AND METHOD FOR ATMOSPHERIC PRESSURE ACTIVE  
ATOM PLASMA PROCESSING FOR SHAPING OF DAMAGED SURFACES  
Docket No.: BEAS-01000US1      Applicant(s): Jeffrey W. Carr  
Appl. No.: Unknown      Attorney: Jason D. Lohr  
Filed: Herewith      Phone: (415) 362-3800  
Express Mail No.: EL622697655US      Sheet 5 of 10



## APPARATUS AND METHOD FOR ATMOSPHERIC PRESSURE ACTIVE ATOM PLASMA PROCESSING FOR SHAPING OF DAMAGED SURFACES

Docket No.: BEAS-01000US1

Applicant(s): Jeffrey W. Carr

Appl. No.: Unknown

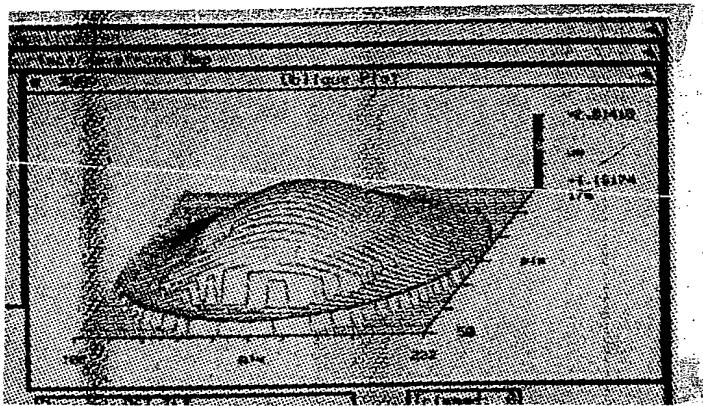
Applicant(s): Jeremy W. Ca  
Attorney: Jason D. Lohr

Filed: Herewith

Attorney: Jason D. Lom  
Phone: (415) 362-3800

Express Mail No.: EL622697655US

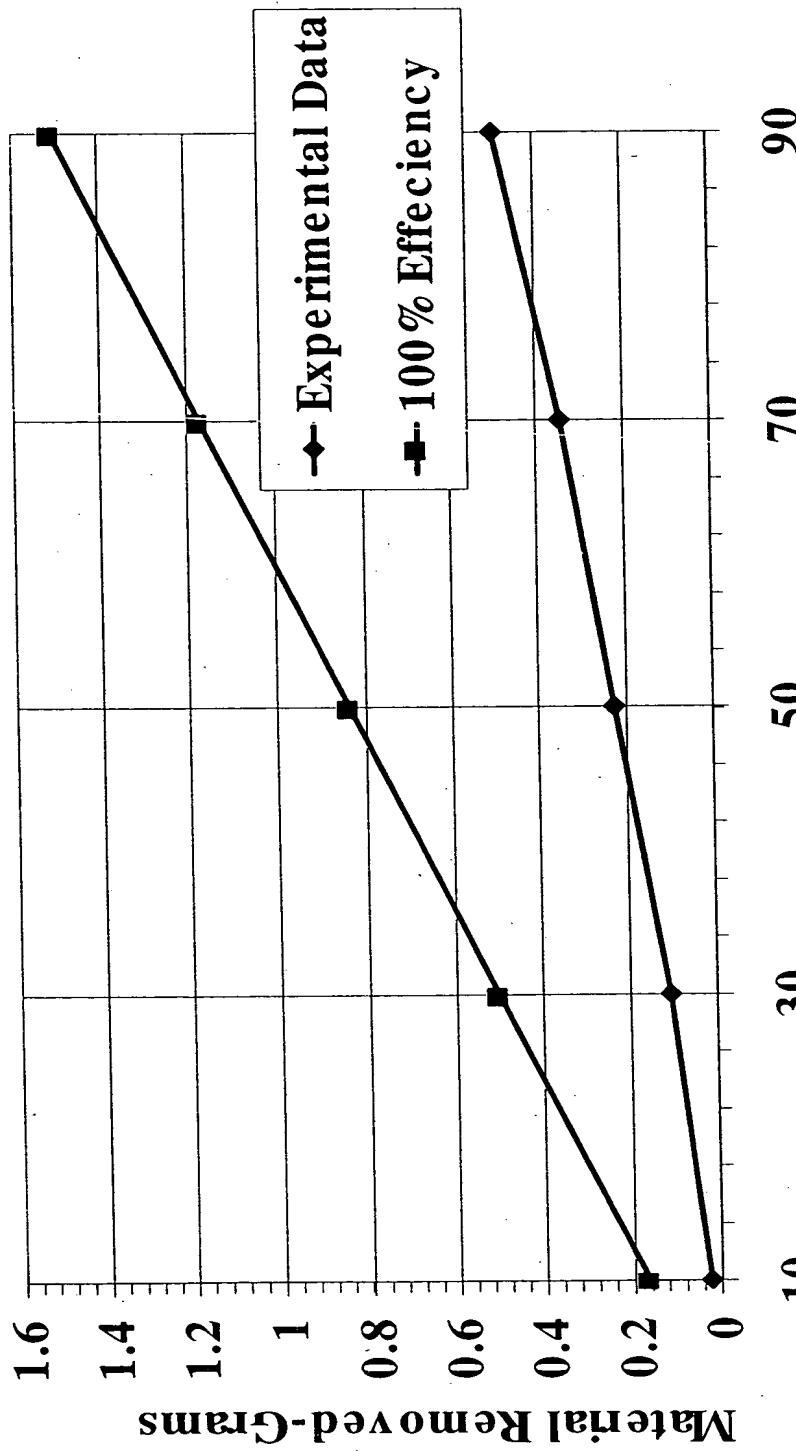
Sheet 6 of 10



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## Effect of Reaction Gas Flow Rate on Removal



Reaction Gas Concentration

KJ 7

## Effect of Distance from Plasma

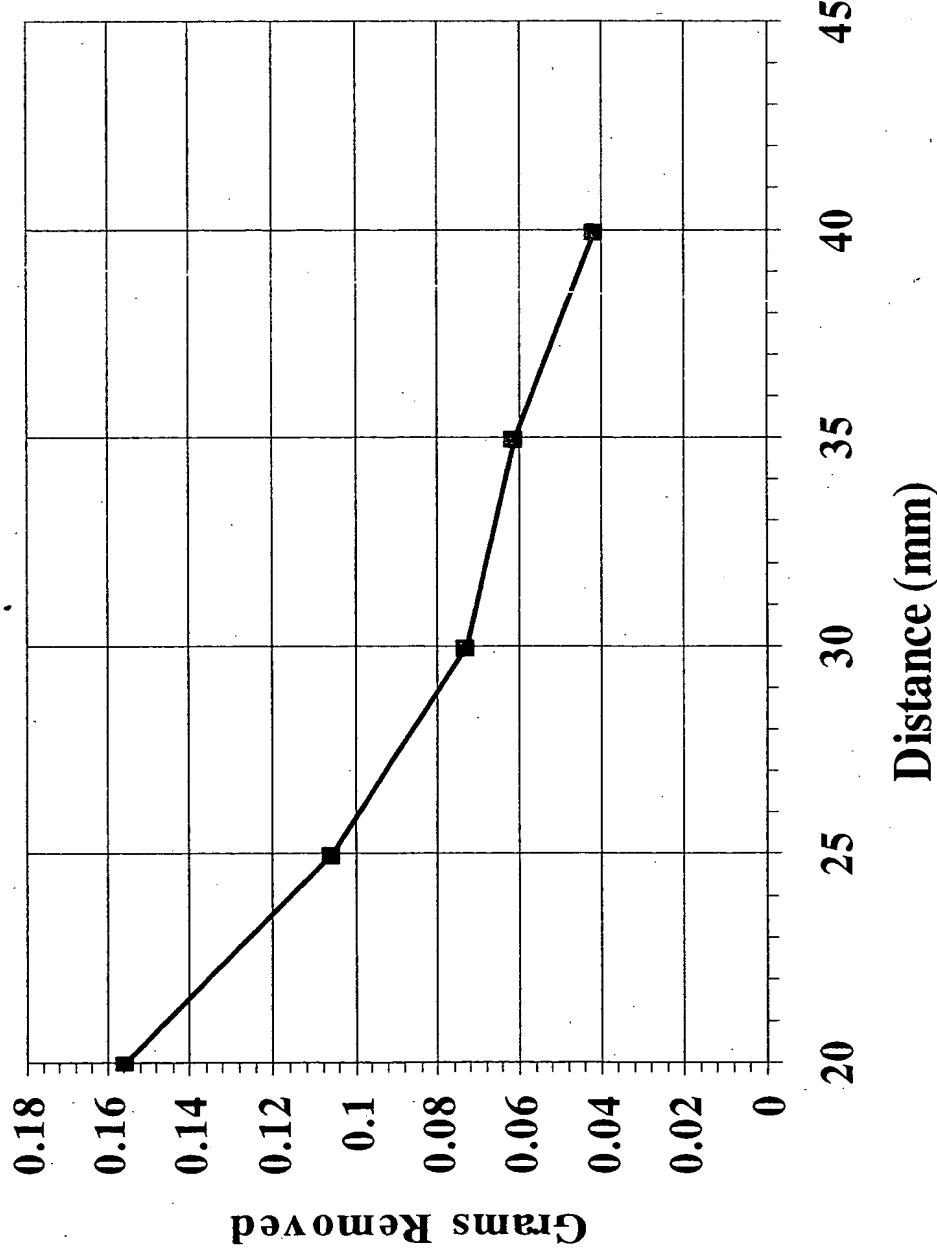
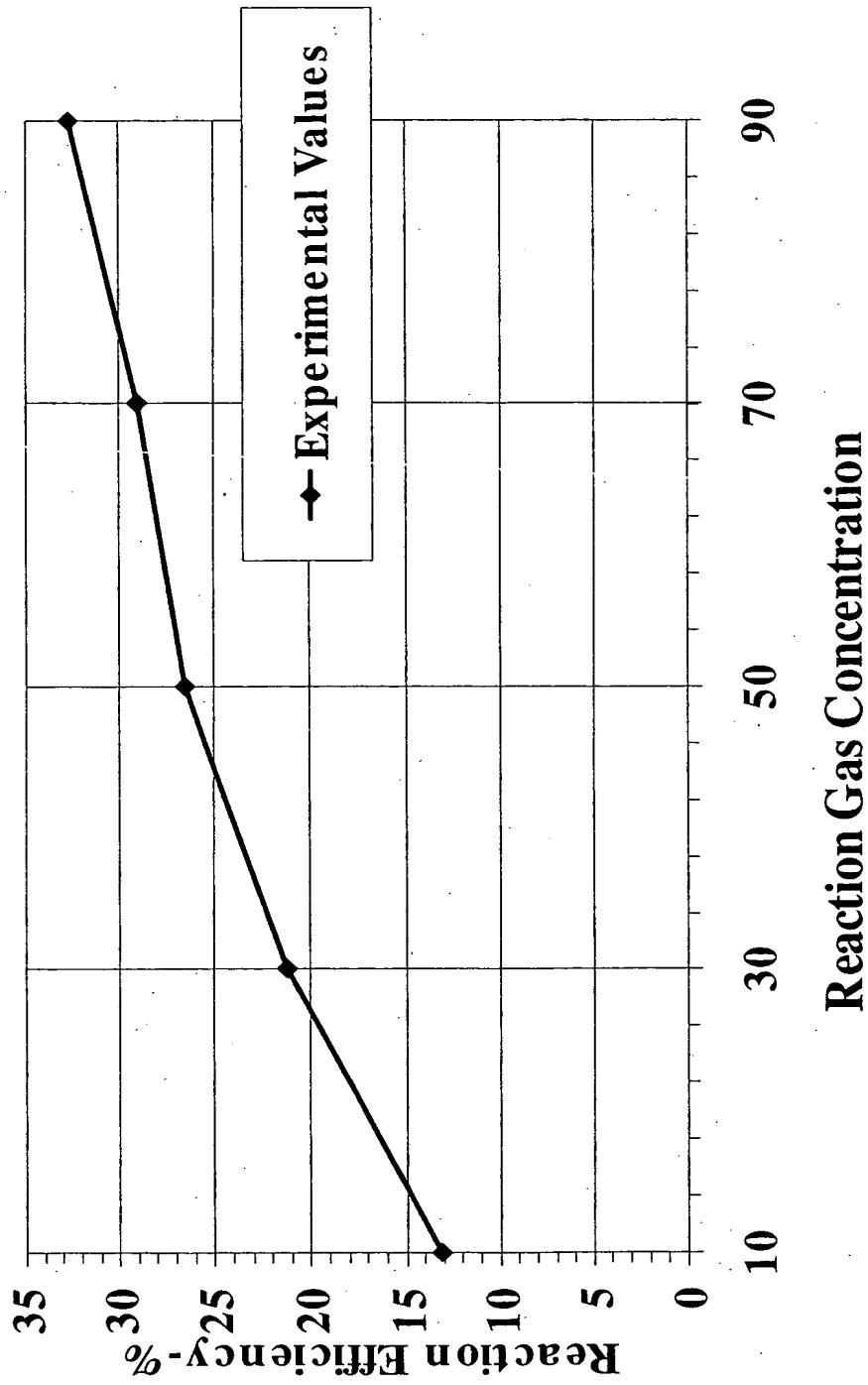


Fig. 8

## Effect of Reaction Gas Flow Rate on Efficiency



Reaction Gas Concentration

69

## Effect of Distance from Plasma on Efficiency

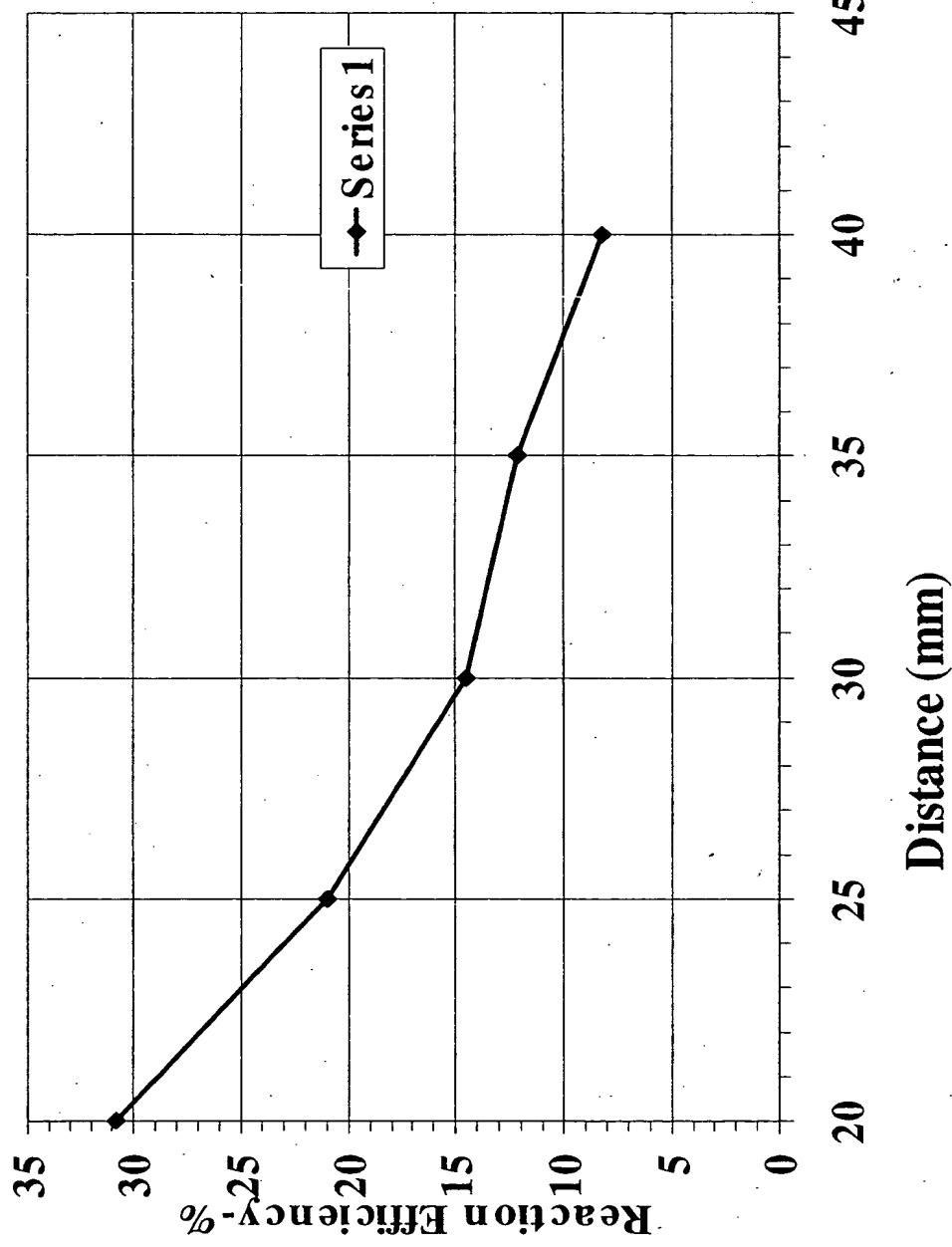


Fig 10